MAR 26 2004
PATENT & TRADEMARK OFFICE

Attorney's Docket No.: 005794 ALRT/ETCH/CONE/ Patent
Confirmation No.: 3777

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

Mark N. Kawaguchi, et al.

Application No: 09/978,121

Filed: October 15, 2001

For: A METHOD OF PHOTORESIST REMOVAL IN THE PRESENCE OF A DIELECTRIC LAYER HAVING A LOW K-VALUE

Examiner: Olsen, Allan W.

Art Unit: 1763

WFEE

Mail Stop: RCE
Commissioner For Patents
P. O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

This is in response to the Final Office Action mailed December 23, 2003, and the Request for Continued Examination (RCE) under 37 C.F.R. § 1.114 filed concurrently herewith. Applicant respectfully requests the Examiner to enter this Amendment and consider the following remarks.

FIRST-CLASS CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first-class mail with sufficient postage in an envelope addressed to Mail Stop: RCE, Commissioner for Patents, P. O. Box 1450, Alexandria, VA 22313-1450, on:

March 23, 2004
Date of Deposit

Dianne Neathery
Name of Person Mailing Correspondence

Dianne Neathery
Signature

March 23, 2004
Date

Pursuant to 37 C.F.R. 1.136(a)(3), applicant(s) hereby request and authorize the U.S. Patent and Trademark Office to (1) treat any concurrent or future reply that requires a petition for extension of time as incorporating a petition for extension of time for the appropriate length of time and (2) charge all required fees, including extension of time fees and fees under 37 C.F.R. 1.16 and 1.17, to Deposit Account No. 02-2666.

Respectfully submitted,

BLAKELY, SOKOLOFF, TAYLOR & ZAFMAN LLP

Date: March 23, 2004

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